

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Patent Application Serial No. 10/726,328
Filing Date December 1, 2003
Inventor Garo J. Derderian et al.
Assignee Micron Technology, Inc.
Group Art Unit Unknown
Examiner Unknown
Attorney Docket No. MI22-2297
Title: Methods of Forming Particle-Containing Materials; and Semiconductor
Constructions Comprising Particle-Containing Materials

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I hereby certify that the following papers are being facsimile transmitted to the Patent and Trademark Office at (703) 872-9306 on the date shown below:

1. Certificate of Facsimile Transmission;
2. Supplemental Information Disclosure Statement w/PTO-1449;
3. Copy of cited reference.

Dated: Dec 31, 2003

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Inventor: **Garo J. Derderian et al.**

Title: **Methods of Forming Particle-Containing Materials; and Semiconductor Constructions Comprising Particle-Containing Materials**

Assignee: **Micron Technology, Inc.**

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SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

PURSUANT TO 37 C.F.R. §§ 1.56, 1.97 AND 1.98

In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, the Examiner's attention is directed to the reference listed on the attached Form PTO-1449 and a copy of which is attached. No admission is made regarding whether the submitted reference is prior art.

This Supplemental Information Disclosure Statement is being filed within three months of the filing date of the application or before the mailing of a first Office Action, whichever occurs last. Therefore, no fee is believed to be required. However, in the event that a fee is required for filing this information disclosure statement, please charge the fee specified under 37 C.F.R. §1.17(p) to Deposit Account No. 23-0925. Please credit Deposit Account No. 23-0925 with any overpayment of the above fee.

Citation of this reference is respectfully requested.

Respectfully submitted,

Date: 12/3/03

Attorney: 

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Form PTO-1490 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				ATTY. DOCKET NO. MW22-2297		SERIAL NO. 10728,328	
APPLICANT: Gero J. Dardarian et al.				FILING DATE: December 1, 2003		GROUP: Unknown	

U.S. PATENT DOCUMENTS							
Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate	
	AA						
	AB						
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FOREIGN PATENT DOCUMENTS							
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						Yes	No
	AM						
	AN						
	AO						
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OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)	
AR	Klaus, J.W. et al., "Atomic Layer Deposition of SiO ₂ Using Catalyzed and Uncatalyzed Self-Limiting Surface Reactions", Surface Review and Letters, Vol. 6, Nos. 3 & 4 (1999), © World Scientific Pub. Co., pp. 435-448.
AS	
EXAMINER	DATE CONSIDERED

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 809. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.